

FORM PTO-1449 U.S. Department of Commerce Patent and Trademark Office				Attorney Docket Number 5347-204		Serial No. not yet assigned	
LIST OF DOCUMENTS CITED BY APPLICANT (Use several sheets if necessary)							
Applicants: Daniel J. C. Hill, et al.							
Filing Date concurrently herewith						Group 1756	
U. S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation Yes No
	1	11-329944	11/30/99	IPO (Abstract in English)	H01L	21/027	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
	2.	J.C.H. Spence et al; Low Energy Point Reflection Electron Microscopy, Surface Review and Letters, Vol. 4, No. 3 (1997) pp 577-587.					
	3.	J.C.H. Spence et al; On the reconstruction of low voltage point projection holograms, Electron Holography, (1995) pp 267-276.					
	4.	Hans-Werner Fink et al; State of the Art Low-Energy Electron Holography, Electron Holography (1995) pp 257-266.					
	5.	J.C.H. Spence et al; Electron Holography at Low Energy, Introduction to Electron Holography, pp 311-331.					
	6.	D.C. Joy et al; Advanced SEM Imaging, Characterization and Metrology for ULSI Technology; 1998 International Conference, pp 653-666.					
	7.	Russell Young et al; The Topografiner: An Instrument for Measuring Surface Microtopography, Review of Scientific Instruments, Volume 43, Number 7, (July 1972) pp 999-1011.					
	8.	Werner Veith et al; Point Projector Electron Microscope, Phy. Rev. Vol. 56, 705 (1939).					

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DATE CONSIDERED

Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Duplicates of
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FORM PTO-1449 U.S. Department of Commerce Patent and Trademark Office				Attorney Docket Number 5347-204		Serial No. 09/781,881	
LIST OF DOCUMENTS CITED BY APPLICANT (Use several sheets if necessary)				<div style="font-size: 2em; font-weight: bold; margin: 0;">RECEIVED</div> <div style="font-size: 1.2em; margin: 5px 0;">JUN 14 2001</div> <div style="font-size: 1.5em; font-weight: bold; margin: 0;">TC 1700</div>			
				Applicants: Daniel J. C. Herr et al.			
				Filing Date February 12, 2001		Group 1645	

U. S. PATENT DOCUMENTS							
Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate	

FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Subclass	Translation Yes No		
11-329944	11/30/99	JPO (Abstract in English)	H01L	21/027			

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3.	J.C.H. Spence et al;	On the reconstruction of low voltage point projection holograms, Electron Holography, (1995) pp 267-276.
4.	Hans-Werner Fink et al;	State of the Art Low-Energy Electron Holography, Electron Holography (1995) pp 257-266.
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8.	Werner Veith et al;	Point Projector Electron Microscope, Phy. Rev. Vol. 56, 705 (1939).

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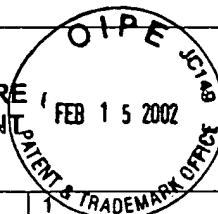
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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

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Sheet 1 of 1



Complete if Known

Application Number	09/781,881
Filing Date	February 12, 2001
First Named Inventor	Daniel J. C. Herr
Group Art Unit	1645
Examiner Name	not yet assigned
Attorney Docket Number	5347-204

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code (if known)			
uv	1.	5,455,850		Howells et al;	10/03/1995	378/34

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Examiner Initials*	Cite No.	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T
		Office	Number	Kind Code (if known)				
uv	2.		JP 09 016062A	A	Patent Abstracts of Japan	01/17/1997		

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T
uv	3.	E. Hecht: "Optics" 1987, Addison-Wesley XP002184727, page 593-596	
uv	4.	Anonymous: "Wafer Conformable Mask Image", Research Disclosure (December 1984) page 609 XP002184726.	
uv	5.	C. Jacobsen et al; "Projection X-Ray Lithography Using Computer-Generated Holograms: A study of compatibility with proximity lithography"; Journal of Vacuum Science and Technology: Part B, Am Inst. of Physics. New York, US vol. 10. No. 6 (11/1/1992) pgs 3177-3181 XP000332529	
uv	6.	C. Jacobsen et al; "X-Ray Holographic Microscopy Using Photoresists", Journal of the Optical Society of America - A, Optical Society of America, Wash. US. vol. 7, no 10 (10/1/1990) pgs 1847-1861 XP000163095.	

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